

Inventor: John T. Moore et al.

Title: Semiconductor Wafer Assemblies Comprising Photoresist Over Silicon Nitride Materials

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 C.F.R. " 1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation application of co-pending application Serial No. 09/995,372, filed November 26, 2001. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: December 11, 2003

By: Jennifer J. Taylor
Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2463		PRIORITY SERIAL NO. 09/995,372	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT John T. Moore et al.			
				PRIORITY FILING DATE November 26, 2001		PRIORITY GROUP 2815	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,219,788	6/93	Abernathy et al.			
	AB	5,045,847	9/91	Tarui et al.			
	AC	5,045,345	9/91	Singer			
	AD	4,996,081	2/91	Ellul et al.			
	AE	3,884,698	5/75	Kakihama et al.			
	AF	5,518,946	5/96	Kuroda			
	AG	5,489,542	2/96	Iwai et al.			
	AH	4,330,569	5/82	Gulett et al.			
	AI	4,499,656	2/85	Fabian et al.			
	AJ	5,554,418	9/96	Ito et al.			
	AK	5,926,739	7/99	Rolfson et al.			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AL	401086562	3/89	Japan			
	AM	362137854	6/87	Japan			
	AN	2129217	5/84	Great Britain			
	AO	2170649	8/86	Great Britain			
	AP	2145243	3/85	Great Britain			
	AQ	403075158	3/91	Japan			
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR		Silicon Proc. for VLSI; 177-178; Vol. 1; S. Wolf				
	AS		Silicon Proc. for VLSI; 191-193; Vol. 1; S. Wolf				
EXAMINER				DATE CONSIDERED			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	4,874,716	10/89	Rao			
	AB	5,587,344	12/96	Ishikawa			
	AC	4,439,270	3/84	Powell et al.			
	AD	5,773,325	6/98	Teramoto			
	AE	5,904,523	5/99	Feldman et al.			
	AF	5,891,793	4/99	Gardner et al.			
	AG	5,795,821	8/98	Bacchetta et al.			
	AH	5,918,147	6/99	Filipiak et al.			
	AI	5,882,978	3/99	Srinivasan et al.			
	AJ	4,612,629	9/86	Harari			
	AK	5,831,321	11/98	Nagayama			
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							Yes No
	AL						
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	AQ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR		Silicon Proc. for VLSI; 37-38; 598-599; Vol. 2; S. Wolf				
	AS		Electronic Materials Science: For Integrated Circuits; 1990 ©; Mayer et al; pp. 269-274; Pub. 1990				
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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	3,549,411	12/70	Bean			
	AB	4,446,194	5/84	Candelaria			
	AC	4,485,553	12/84	Christian			
	AD	4,543,707	10/85	Ito et al.			
	AE	5,098,865	3/92	Machado et al.			
	AF	5,160,998	11/92	Itoh et al.			
	AG	5,306,946	4/94	Yamamoto			
	AH	5,442,223	8/95	Fujii			
	AI	5,523,616	6/96	Den			
	AJ	5,756,404	5/98	Friedenreich et al.			
	AK	5,834,374	11/98	Cabral Jr. et al.			

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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
	AR		Intrinsic Stress in Silicon Nitride and Silicon Dioxide Films Prepared by Various Deposition Techniques; 1988 IEEE Internatl. Sympos. On Electrical Insulation, Boston, MA; June 5-8, 1988; 1 page; Kanicki, J. et al.
	AS		Passivation of GaAsFET's with PECVD Silicon Nitride Films of Different Stress States; IEEE Transactions on Electron Devices; Vol. 35, No. 9; Sept. 1988; pp. 1412-1418

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	AA	4,695,872	Chatterjee				
	AB	5,178,016	Dauenhauer et al.				
	AC	5,985,771	Moore et al.				
	AD	3,649,884	Haneta				
	AE	4,868,632	Hayashi				
	AF	5,304,829	Mori et al.				
	AG	5,925,494	Horn				
	AH	4,075,367	Gulett				
	AI	4,732,858	Brewer et al.				
	AJ	6,300,253	Moore, John T.				
	AK	4,698,787	Mukherjee et al.				

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	AQ						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
AR		Silicon Nitride Overcoats for Thin Film Magnetic Recording Media; IEEE Transactions on Magnetics; Vol 27. No. 6, Nov. 1991; pp. 5070-5072	
AS			

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EL 979950548

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	AA	4,939,559	07/90	DiMaria et al.				
	AB	6,140,181	10/00	Forbes et al.				
	AC	6,143,627	11/00	Robinson				
	AD	5,877,069	03/99	Robinson				
	AE	6,093,956	07/00	Moore et al.				
	AF	6,103,619	08/00	Lai				
	AG	6,265,241	07/01	Pan				
	AH	6,420,777		Lam et al.				
	AI	6,417,559	07/02	Moore et al.				
	AJ	5,041,888	08/91	Possin et al.				
	AK	6,143,662	11/00	Rhodes et al.				
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